

METHOD AND APPARATUS FOR SUPPORTING A  
SEMICONDUCTOR WAFER DURING PROCESSING

Granneman et al.

Appl. No.: Unknown

Atty Docket: ASMINT.002C3

fig-1

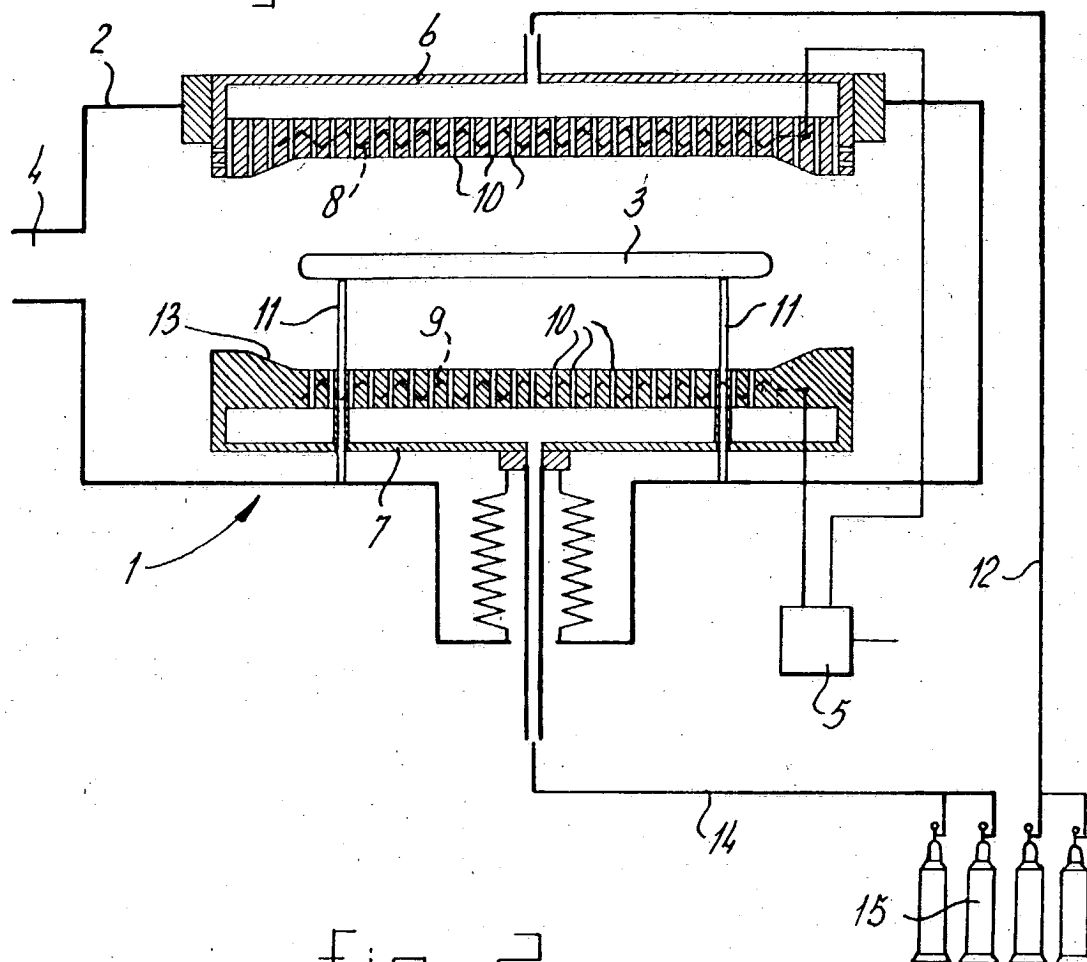
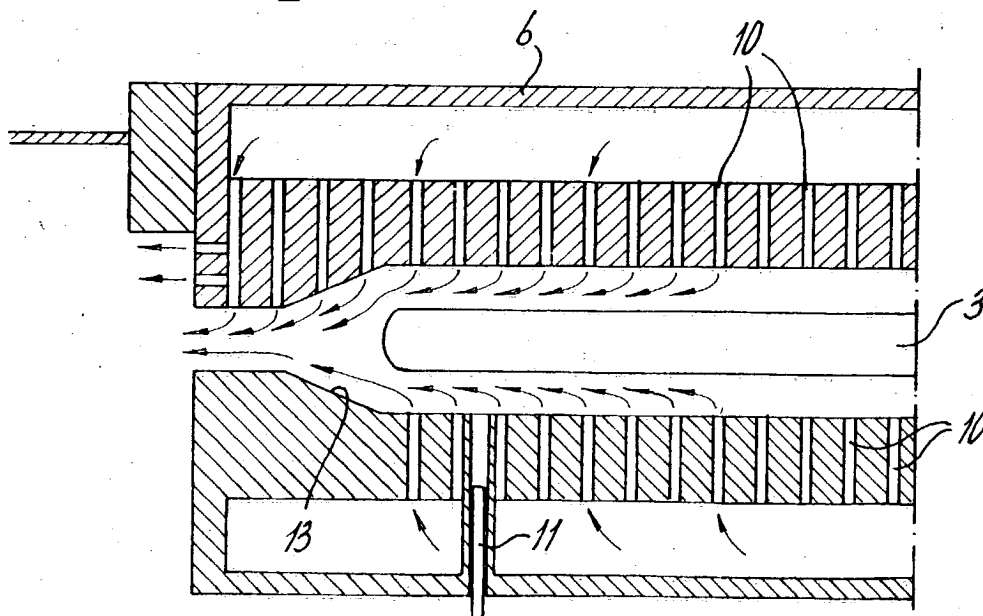


fig-2



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fig-3

